

**RESPONSE UNDER 37 C.F.R. 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2811**

Attorney Docket No. 5649-1286

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Park et al.

Confirmation No.: 5520

Serial No.: 10/828,596

Group Art Unit: 2811

Filed: April 21, 2004

Examiner: Ori Nadav

For: METHODS OF FORMING METAL THIN FILMS, LANTHANUM OXIDE FILMS  
AND HIGH DIELECTRIC FILMS FOR SEMICONDUCTOR DEVICES USING  
ATOMIC LAYER DEPOSITION

Date: August 31, 2009

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AFTER FINAL OFFICE ACTION  
PURSUANT TO 37 C.F.R. § 1.116**

Sir:

This Amendment is submitted in reply to the final Office Action dated July 14, 2009. Applicants respectfully request reconsideration of the application in view of the remarks submitted herein.

It is not believed that any fee(s), including fees for additional claims, are required, beyond those that may otherwise be provided for in documents accompanying this submission. In the event, however, that any requests, petitions or extensions of time for the accompanying response are required to prevent abandonment of this application, Applicants submit that such an extension is also hereby petitioned for under 37 C.F.R. §1.136(a) and/or a request be granted pursuant to 37 C.F.R. §1.114. Any additional fees believed to be due in connection with this submission may be charged to our Deposit Account No. 50-0220, or any overpayment may be credited to the same.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this document.

**Remarks/Arguments** begin on page 12 of this document.